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Front Matter: Volume 9627

, "Front Matter: Volume 9627," Proc. SPIE 9627, Optical Systems Design
2015: Advances in Optical Thin Films V, 962701 (14 October 2015); doi:
10.1117/12.2220811

SPIE.

Event: SPIE Optical Systems Design, 2015, Jena, Germany

PROCEEDINGS OF SPIE

Optical Systems Design 2015: Advances in Optical Thin Films V

Michel Lequime
H. Angus Macleod
Detlev Ristau
Editors

7–10 September 2015
Jena, Germany

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SPIE

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European Optical Society (Finland)
Fraunhofer IOF (Germany)
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Published by
SPIE

Volume 9627

Proceedings of SPIE 0277-786X, V. 9627

SPIE is an international society advancing an interdisciplinary approach to the science and application of light.

Optical Systems Design 2015: Advances in Optical Thin Films V, edited by Michel Lequime,
H. Angus Macleod, Detlev Ristau, Proc. of SPIE Vol. 9627, 962701 · © 2015 SPIE
CCC code: 0277-786X/15/\$18 · doi: 10.1117/12.2220811

Proc. of SPIE Vol. 9627 962701-1

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Author(s), "Title of Paper," in *Optical Systems Design 2015: Advances in Optical Thin Films V*, edited by Michel Lequime, H. Angus Macleod, Detlev Ristau, Proceedings of SPIE Vol. 9627 (SPIE, Bellingham, WA, 2015) Six-digit Article CID Number.

ISSN: 0277-786X

ISSN: 1996-756X (electronic)

ISBN: 9781628418163

Published by

SPIE

P.O. Box 10, Bellingham, Washington 98227-0010 USA

Telephone +1 360 676 3290 (Pacific Time) · Fax +1 360 647 1445

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